

**IN THE CLAIMS:**

No claims are currently amended:

1. (Previously presented) A scanning charged-particle microscope having  
a charged-particle source,  
a lens for focusing the charged-particle beam emitted from said charged-particle source,  
and  
a scanning deflector for scanning said charged-particle beam in two-dimensional form on  
a sample,  
wherein said scanning charged-particle microscope is characterized in that a passage  
aperture for limiting the passage of the charged-particle beam is located between the charged-  
particle source and said scanning deflector, and in that a member for limiting the passage of the  
charged-particle beam is provided at least in the center of said passage aperture, and  
an image of said sample is obtained by scanning said charged-particle beam having  
passed through said passage aperture on said sample using said scanning deflector.
2. (Previously presented) A scanning charged-particle microscope as set forth in Claim 1  
above, wherein the scanning charged-particle microscope is characterized in that the half-  
opening angle of said aperture for said charged-particle beam focused on a sample by said  
focusing lens has a band with respect to specific values of  $\alpha_a$  and  $\alpha_b$ .
3. (Previously presented) A scanning charged-particle microscope as set forth in Claim 1  
above, wherein the scanning charged-particle microscope is characterized in that said passage  
aperture is formed in a plate-like body, and in that said plate-like body is formed movably with  
respect to said charged-particle beam.
4. (Original) A scanning charged-particle microscope as set forth in Claim 3 above,  
wherein the scanning charged-particle microscope is characterized in that said plate-like body is  
provided with a circular aperture in addition to said passage aperture.

5. (Previously presented) A scanning charged-particle microscope having  
a charged-particle source,  
a lens for focusing the charged-particle beam emitted from said charged-particle source,  
and  
a scanning deflector for scanning said charged-particle beam in two-dimensional form on  
a sample,  
wherein said scanning charged-particle microscope is characterized in that it has a means,  
located between the charged-particle source and said scanning deflector, by which said charged-  
particle beam focused on said sample is radiated so that the half-opening angle of said aperture  
for the charged-particle beam will have a band with respect to specific values of  $\alpha_a$  and  $\alpha_b$ , and  
an image of said sample is obtained by scanning said charged-particle beam which is cut off said  
band of said half-opening on said sample using said scanning deflector

6. (Original) A scanning charged-particle microscope as set forth in Claim 5 above,  
wherein the scanning charged-particle microscope is characterized in that a plate-like aperture  
body in which an annular aperture is formed is provided between said charged-particle source  
and said scanning deflector.

7. (Previously presented) A scanning charged-particle microscope as set forth in Claim 6  
above, wherein the scanning charged-particle microscope is characterized in that in addition to  
said annular aperture, a circular aperture is provided in said plate-like aperture body, and in that  
there is provided a movement feature for positioning said annular aperture and said circular  
aperture on the orbit of said charged-particle beam.

8. (Previously presented) A scanning charged-particle microscope having  
a charged-particle source,  
a lens for focusing the charged-particle beam emitted from said charged-particle source,  
and  
a scanning deflector for scanning said charged-particle beam in two-dimensional form on  
a sample,  
wherein said scanning charged-particle microscope is characterized in that an aperture,

located between the charged-particle source and said scanning deflector, for limiting the passage of said charged-particle beam is formed in two different places on the orbit thereof, and in that one of said two apertures is an annular aperture and the other is a circular, and

an image of said sample is obtained by scanning said charged-particle beam having passed through said annular aperture on said sample using said scanning deflector.

9. (Previously presented) A scanning charged-particle microscope as set forth in Claim 8 above, wherein the scanning charged-particle microscope is characterized in that said annular aperture is formed in a plate-like body, in that said plate-like body is also provided with a circular aperture, and in that there is provided a movement feature for positioning the annular aperture and the circular aperture on the orbit of said charged-particle beam.

10. (Previously presented) A scanning charged-particle microscope as set forth in Claim 8 above, wherein the scanning charged-particle microscope is characterized in that said circular aperture is formed in a plate-like body, in that said plate-like body is also provided with a charged-particle beam cutoff portion, and in that there is provided a movement feature for positioning said charged-particle beam cutoff portion and said circular aperture on the orbit of said charged-particle beam.

11. (Previously presented) A scanning charged-particle microscope as set forth in Claim 8 above, wherein the scanning charged-particle microscope is characterized in that said circular aperture and said annular aperture are formed in a first plate-like body and a second plate-like body, respectively, in that said first plate-like body is provided with a charged-particle beam cutoff portion in addition to the circular aperture and said second plate-like body is provided with a circular aperture in addition to the annular aperture, and in that both the first plate-like body and the second plate-like body are provided with a movement feature.

12. (Previously presented) A samples image forming method using a scanning charged-particle microscope having

a charged-particle source,

a lens for focusing the charged-particle beam emitted from said charged-particle source,

and

a scanning deflector for scanning said charged-particle beam in two-dimensional form on a sample,

wherein said samples image forming method is characterized in that the image of a sample that has been acquired by scanning said charged-particle beam having passed through an annular aperture on said sample using said scanning deflector, said annular aperture being positioned on the orbit of the charged-particle beam and between said charged particle source and said scanning deflector, and the image of a sample that has been acquired with a circular aperture positioned on the orbit of the charged-particle beam are combined to form a new samples image.